



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

CHO ET AL. Atty. Ref.: 4105-73; Confirmation No. 6675

Appl. No. 10/568,770 TC/A.U. 1795

Filed: February 21, 2006 Examiner: George

For: FERROELECTRIC THIN-FILM PRODUCTION METHOD, VOLTAGE-APPLICATION
ETCHING APPARATUS, FERROELECTRIC CRYSTAL THIN-FILM SUBSTRATE,
AND FERROELECTRIC CRYSTAL WAFER

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September 8, 2008

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT

Applicants hereby submit this in response to the Office Action mailed May 9, 2008
("Office Action").

A response to the Office Action was originally due August 9, 2008. Applicants hereby
petition for a one-month extension of time in which to submit a response or an amendment in
response to the Office Action. The fee for a one-month extension of time is \$120 and a check in
that amount is enclosed. Therefore, the deadline for responding to the Office Action is now
September 9, 2008. Accordingly, this Amendment and Response is being timely filed.

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